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Enhancing the photocatalytic activity of GaN by electrochemical

etching

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Graphical abstract



Nanoporous (NP) GaN thin films prepared via electrochemical etching method were first investigated as photocatalysts. The nanostructures exhibited excellent stability and good photocatalytic activity in dye photodegradation.

Highligts

Nanoporous (NP) GaN thin films showed better photocatalytic activity than GaN thin films. NP GaN exhibited good ability to photodegrade organic dye at various pHs.

NP GaN had much better photocatalytic activity and more excellent stability than porous Si.

Abstract

Nanoporous (NP) GaN thin films prepared with electrochemical etching method were investigated as photocatalysts in dye photodegradation systematically. The comparison of NP GaN thin films with GaN thin films showed that NP GaN thin films with high surface-to-volume ratio exhibited much better photocatalytic activity. In comparison with porous Si wafers, NP GaN thin films with lower surface area exhibited much better photocatalytic activity, because GaN is efficient not only for dye reduction like Si, but also for dye oxidation. Due to its ceramic-like chemical inertness, moreover, NP GaN showed more excellent stability to photodegrade organic dye than porous Si under basic conditions. The band gap of GaN can be modulated in visible-light region, which will be beneficial to a photodegradation system with concentrated solar light.

Keywords

Nanoporous GaN; Photocatalytic activity; Porous Si; Electrochemical etching

1. Introduction

Research on porous semiconductors has drawn much attention, since the discovery of intense luminescence from porous Si [1, 2]. The high surface area, band gap shift, and efficient luminescence suggest uses of porous semiconductors over a wide range extending from optoelectronics to chemical and biochemical sensors applications. Another attractive application of porous semiconductor materials is in environmental remediation and hydrogen production because their high surface-to-volume (S/V) ratio results in enhanced photocatalytic effect [3]. Porous nanostructure fabricated via an electrochemical etching process is generally adhered to a rigid substrate so that this nanostructure can be easily recycled and reused in environmental remediation and hydrogen production. Nowadays, porous Si has attracted much interest because of its potential in utilizing solar energy to degrade organic pollutants [4, 5]. However, chemical properties of porous Si are unstable under harsh conditions such as low and high pH, which limits its application.

GaN is a well-known wide band-gap semiconductor that has a bandgap energy of 3.4 eV at room temperature. The conduction band minimum (E_{CBM}) of GaN is higher than that of $E^{\circ}(OH \cdot / OH^{\circ})$ (-0.28 versus NHE), whereas the valence band minimums (E_{VBM}) of GaN is lower than that of $E^{\circ}(O_2/O_2^{\bullet})$ (2.27 V versus NHE) [6, 7]. Based on such a realization, GaN has been used to split water for the generation of hydrogen gas and decompose organic pollutants into harmless compounds such as carbon dioxide and water [8, 9]. Due to the ceramic-like chemical inertness, moreover, it has exhibited much better stability than semiconductors based on metal oxides, such as ZnO and TiO₂, under acidic conditions [9]. Most important of all, the band gap

tunability by alloying with InN allows efficient absorption of solar spectrum. Therefore, NP GaN should be intriguing as a photocatalytic material because of its simple fabrication step as well as expected advantages of GaN nanostructures in photodegradation for organic pollutants.

In this study, we reported the fabrication of NP GaN thin films by electrochemical etching in HF solution, and its photocatalytic activity for direct fast scarlet 4BS dye was characterized. In comparison with porous Si wafers, NP GaN thin films exhibited more excellent chemical stability, and much better photocatalytic efficiency. It implied that NP GaN and its alloys are promising photocatalytic materials under concentrated solar light intensity.

2. Experimental

2.1 Fabrication of NP GaN thin films

Electrochemical (EC) porosification experiments were conducted in a two-electrode cell at room temperature with n-type GaN (0002) thin films or n-type Si (100) wafers (the resistivity of 0.5-1 Ω cm) as the anode and a platinum wire as the counter electrode (cathode) [10, 11]. The structure of n-type GaN films is that Ga-polar Si doped GaN of 2 μ m thickness was grown on c-plane sapphire with undoped GaN layer of 500 nm used as an etch stop by metal-organic chemical vapor deposition (MOCVD) with a doping density of 8×10¹⁸ cm⁻³ [12]. The electrolytes were prepared by adding ethanol to HF (49%) with a volume ratio of 1:1. The anodization process was carried out in a potentiostatic (constant voltage) mode controlled by a Gwinstek GPD-3303S source meter. After anodization, samples were rinsed with deionized water and dried in N₂. Morphology of the samples was characterized with atomic force microscope (AFM) (NanoScope IIIA) and scanning electron microscope (SEM) (Hitachi SU-70). Photoluminescence (PL) spectroscopy measurements with a He-Cd laser emitting at 325 nm were performed to identify the

optical characteristics of NP GaN thin films.

2.2 Evaluation of the photocatalytic activity

The molecule structure of direct fast scarlet 4BS (>90% purity) is shown in the following

[13].



There are N=N double bonds which are chromophoric group, phenyl rings and naphthyl rings in the structure of 4BS dye. The corresponding UV-Vis absorption peaks are centered at \sim 498, \sim 334 and \sim 208 nm, respectively.

The photocatalytic experiments were carried out with the NP GaN films and the porous Si wafers with the area of 1 cm² in a 4 ml 4BS dye solution in a sealed quartz tube, under stirring. The initial concentration of 4BS dye solution was about 1.5×10^{-5} mol L⁻¹. The reaction system was irradiated under ultraviolet light using a 30 W Hg lamp ($\lambda > 254$ mm). The concentration of 4BS dye was determined by UV-Vis spectrophotometer (UV-2450, Shimadzu, Japan). All of the photocatalytic reactions were carried out under air ambient and at room temperature.

3. Results and discussion

3.1 Characterization of NP GaN thin films

To evaluate the morphology and structure of NP GaN thin films prepared via the EC etching technique at 5, 10, 30 and 50 V for 1 min, SEM and AFM measurements were performed. Figs. 1(a)-1(d) show the top view SEM images of the NP GaN films. The SEM image shown in Fig. 1(a) indicates that the applied bias of 5 V is not sufficient to induce local breakdown which leads to the pore formation [14]. The root-mean-square (rms) roughness of the film surface measured on a 3×3

 μ m area, using AFM, is 6 nm. By increasing the applied biases from 10 to 50 V, the density and diameter of GaN nanopores vary from 1.44×10^{10} /cm² to 4.9×10^{10} /cm², and from 17.5 nm to 35 nm, respectively (Table 1). The variations are ascribed to a stronger electric field that initiates more avalanche breakdown events per unit time [15].

Figs. 1(e)-1(h) show the cross-sectional images of the corresponding left samples. In Fig. 1(f), the etching depth along the $[000\overline{1}]$ direction is about 100 nm at 10 V. At 30 and 50 V, the nanopores with approximate 2 μ m in length are uniform, straight and vertical to the substrate surface, indicating that the etching rate depends on the applied bias. The trajectory of the pore can be considered as a mapping of the electric field/carrier flow contours, so a higher applied bias reflects a higher carrier rate which leads to a higher etching rate [16].

Fig. 2 displays the room-temperature PL spectra of NP GaN samples fabricated under the different applied biases. The NP GaN samples obtained at high applied bias are observed to be red-shifted relative to the samples fabricated at low applied bias. The red-shifted can be attributed to the relaxation of the compressive stress in the porous samples, which can be further confirmed by Raman scattering [17] and X-ray diffraction [18]. On the other hand, the PL intensity for the etched samples are found to be increased, which could mainly be attributed to the enhancement of the photon extraction efficiency due to more photons scattering from the sidewalls of the NP GaN [19].

3.2 Photocatalytic activity of NP GaN thin films

The photocatalytic activity of GaN thin films etched at the different applied biases was compared by measuring the amount of dye solutions photodegraded by the etched GaN films under UV light illumination. Figs. 3(a) and 3(b) show the removal amount of 4BS under different

irradiation times and the absorption spectra of 4BS solutions degraded for 8 h, respectively. After 8 h of UV illumination, the amount of organic dye degraded by GaN samples increases from 26% to 57% with pore density rising from 0 to 4.9×10^{10} /cm², whereas the linear increases of removal amount indicate that the prolonged photodegraded times can lead to further increase of removal amount (see Fig. 3(a)). The high photocatalytic activity of NP GaN thin films obtained at 50 V presumably results from the high S/V ratio of GaN nanopores.

The process of photodegradation can be roughly divided into four different stages (Fig. 4) [7]. Stage I is photoexcitation in the nanopores, at which electron-hole pairs are created by UV light illumination (with photo energy greater than the bandgap energy, E_g), transforming the catalyst into the photoexcited state (eqn. 1). Stage II is that the electron-hole pairs are separated and subsequently transferred to their sites on the internal surface of GaN nanopores. In parallel to stage II, stage III is charge recombination, where a fraction of photogenerated electrons and holes radiatively or nonradiatively recombine, or are trapped by the defects on the internal surface of GaN nanopores. Stage IV is the redox reaction, at which further react with adsorbed water and dissolved oxygen to produce **•OH** radicals (eqns. 2-7) which are strong and nonselective oxidizing agents for organic pollutants. Finally, 4BS molecules are oxidized and decomposed by the **•OH** radicals (eqn. 8).

$$GaN \xrightarrow{h\nu} h^+ + e^-$$
(1)

 $\mathbf{h}^+ + \mathbf{H}_2 \mathbf{0} \rightarrow \mathbf{0} \mathbf{H} + \mathbf{H}^+, \tag{2}$

 $h^+ + OH^- \rightarrow OH \tag{3}$

 $\mathbf{e}^- + \mathbf{O}_2 \to \mathbf{O}_2^-, \tag{4}$

$$\bullet \mathbf{0}_{\mathbf{2}}^{-} + \mathbf{H}^{+} \to \bullet \mathbf{00H} \tag{5}$$

$$e^- + OOH + H^+ \rightarrow H_2O_2 \tag{6}$$

 $H_2 O_2 + e^- \rightarrow OH + OH^-$ (7)

$$4BS + OH \rightarrow degradation products$$
 (8)

Fig. 5 shows the dependence of photocatalytic activity of NP GaN thin films obtained at 50 V in acidic and basic solutions. The amount of photodegraded dye in acidic solutions with pH of 2.0, 3.0, and 5.0 is 78, 82, and 70 %, respectively, whereas the amount in pH 9 solution is 41%. This indicates that the photocatalytic activity of NP GaN is more effective under acidic than basic conditions. Under the acidic conditions, it is easy to form N-H groups on the internal surface of GaN nanopores, so this pH dependence of the photocatalytic reaction may result from a sequence of proton-transfer events from the N-H groups to the nearby OH groups and bulk water molecules [20].

We investigated the changes in surface morphology and crystal structure of NP GaN thin films obtained at 50 V using SEM (Fig. 6) and XRD (Fig. 7) before and after photodegradation at pH 2. As shown in Figs. 6 and 7, there are no apparent changes in surface morphology and diffraction peaks, which can be also observed under basic conditions. Therefore, these results indicate that NP GaN has stability to photodegrade organic dye under strong acidic or basic conditions, which is in agreement with the photocatalytic stability of GaN nanowires [9].

3.3 Comparison of the photocatalytic activity of NP GaN with that of porous Si

The photocatalytic activity of NP GaN thin films was compared with that of porous Si wafers because porous Si wafers have exhibited a very strong photocatalytic activity for some organic pollutants such as methyl red (MR), phenol, and methyl orange (MO) [4, 5, 21]. Porous Si (100)

wafers were fabricated via the EC etching technique at 15 V for 10 min. Fig. 8 shows the typical top-view and cross-sectional SEM images of porous Si with a diameter of averagely 300 nm, a pore density of 7.9×10^{9} /cm², and a pore depth of 60 µm. For the porous Si with the area of 1 cm², its internal surface area is larger than that of NP GaN obtained at 50 V. We measured the absorption spectra of 4BS dye solutions photodegraded by the NP GaN and the porous Si. Our observations clearly show that (i) NP GaN exhibits 57% potodegradation of chromophoric structure (λ =494 nm) of organic dye, whereas porous Si photodegrades only 33% of the dye (Fig. 9); (ii) the naphthalene and benzene rings can be photodegraded by NP GaN thin films, but absorbance of aromatic rings in 4BS solutions degraded by porous Si exhibits significant increase (Fig. 9), which may be explained by the formation of intermediate products such as $(-\infty)^{N_0} + (-\infty)^{N_0} + (-\infty)^$

To evaluate presumably photodegradation mechanisms of NP GaN and porous Si, band levels of GaN and Si are shown in Fig. 10. The E_{CBM} values of GaN and Si are higher than that of $E^{\circ}(OH/OH)$, whereas the E_{VBM} value of GaN is lower than that of $E^{\circ}(O_2/O_2^{\bullet})$ [6, 7]. Porous Si has higher band-gap energy (1.7-1.9 eV) than bulk Si (1.1 eV) [23], but its E_{VBM} value is still higher than that of $E^{\circ}(O_2/O_2^{\bullet})$. Therefore, GaN is efficient not only for dye reduction like Si (eqns. 4-8), but also for dye oxidation (eqns. 2, 3 and 8). Furthermore, after the photodegradation experiment under the basic condition, there is no significant change in the surface morphology of NP GaN, whereas the porous Si layers are dissolved, indicating that NP GaN has more excellent stability than porous Si.

4. Conclusions

In summary, the photocatalytic activity of NP GaN thin films was investigated for the use of NP GaN thin films as photocatalysts in harsh environments. NP GaN thin films exhibited higher photocatalytic activity than GaN thin films because of their larger surface area, which enhanced hole transport from photocatalyst to dye solution. Furthermore, NP GaN showed higher efficiency and stability than porous Si due to its large band gap energy and ceramic-like chemical inertness. This behavior would be beneficial to a photodegradation system with concentrated solar light.

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Figure captions

Fig. 1. Plan-view SEM images of GaN samples obtained by the EC etching process at (a) 5 V, (b)

10 V, (c) 30 V and (d) 50 V. (e)-(f) show cross-sectional view of the corresponding left images.

Fig. 2. PL spectra of nanoporous GaN fabricated at the different applied biases.

Fig. 3. (a) Removal amount of 4BS by the etched GaN samples under the different irradiation times. (b) Absorption spectra of 4BS solution photodegraded by the etched GaN samples for 8 h.

Fig. 4. Schematic illustrating the mechanism for photocatalytic process in GaN nanopores. (I) photoexcitation in the nanopores, (II) charge separation and transportation, (III) charge recombination in parallel to stage II, and (IV) photoassisted redox reaction.

Fig. 5. Amount of 4BS photodegraded by NP GaN at 50 V under various pHs.

Fig. 6. SEM images of NP GaN obtained at 50 V (a) before the photocatalytic reaction and (b) after the reaction at pH 2 for 8 h.

Fig. 7. XRD patterns of NP GaN obtained at 50 V before and after the photocatalytic reaction at pH 2 for 8 h.

Fig. 8. (a) Plan-view and (b) cross-sectional SEM images of porous Si fabricated by the EC etching process at 15 V.

Fig. 9. Absorption spectra of 4BS solution photodegraded by porous Si and NP GaN.

Fig. 10. Band gaps (eV) and redox potentials of GaN and Si using the normal hydrogen electrode (NHE) as a reference [6, 7]. This figure can't indicate that the E_{CBM} of NP GaN is higher or lower than that of porous Si.

Tables

Table 1 Comparison of pore density, pore diameter, and photocatalytic activity of GaN samples

applied bias	rms surface	pore density	pore diameter
(V)	roughness ^b (nm)	(cm^{-2})	(nm)
-	-	-	-
5	6	0	0
10	-	1.4×10 ¹⁰	17
30	-	4.7×10 ¹⁰	24
50	-	4.9 × 10¹⁰	35
	applied bias (V) - 5 10 30 50	applied biasrms surface roughness ^b (nm)5610-30-50-	applied biasrms surfacepore density(V)roughness ^b (nm)(cm ⁻²)56010- 1.4×10^{10} 30- 4.7×10^{10} 50- 4.9×10^{10}

obtained at the different conditions

^a Corresponds to samples in Fig.1

^b The root-mean-square (rms) surface roughness was determined by atomic force microscopy

measured on a $3 \times 3 \mu$ m area.



Figure 2



Figure 3



Figure 4



Figure 5





Figure 7







